

SiP Activities in ITRI

ERSO/ITRI

廖錫卿

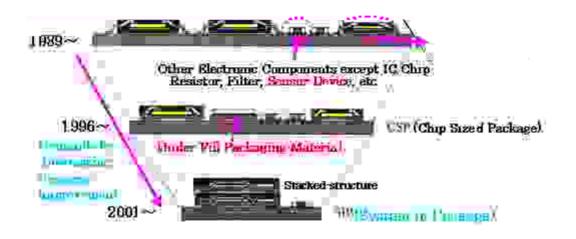
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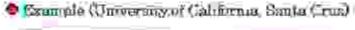
Outline

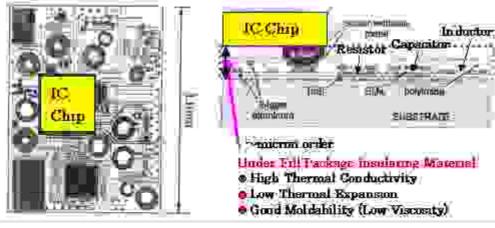
- SiP Product/Technology Trends & Opportunities
- Bottlenecks & Breakthrough
- SiP Activities in ITRI
- Design Flow & Environment
- Accomplishment in SiP for RF Applications
- Complete Infrastructure of IC Industry
- SiP Consortium
- Strategy
- Action Plan



System-in-Package (SiP)



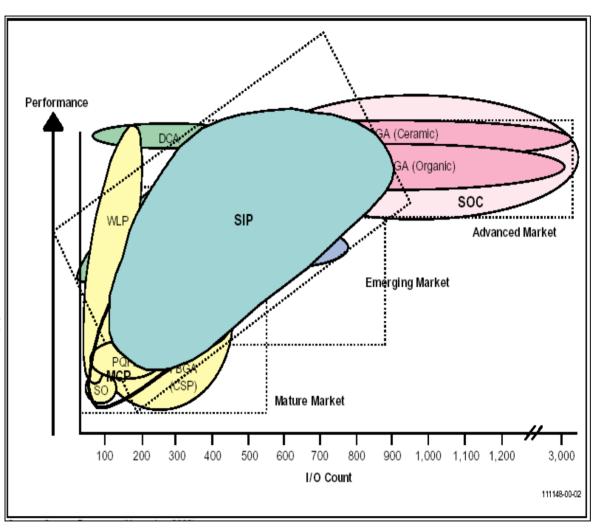






Why SiP?

- Product Trends
- Compact in Size
- Highly Integration
- Alternatives for SoC
- Quick Time-to-market

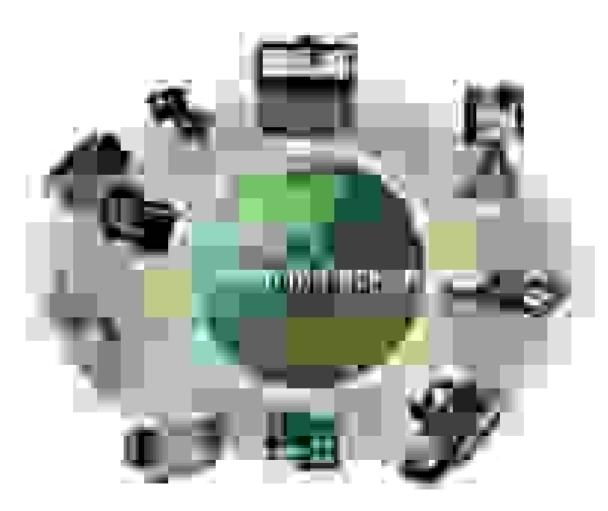


Source: Dataquest 2002



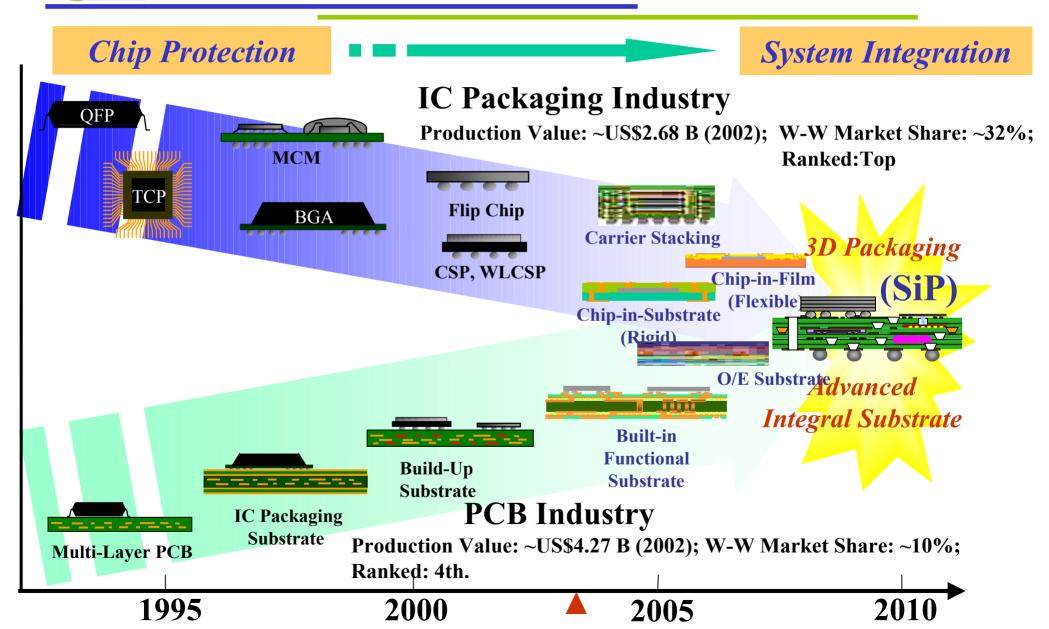
Driving Force: Size, Cost, Performance

More in Handheld Devices:





Technology Trend in Semiconductor Packaging Industry

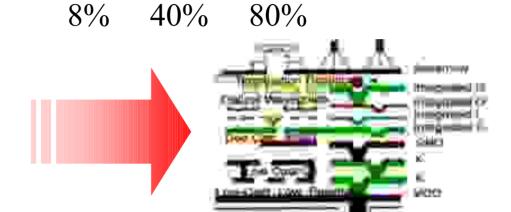




Integration of Passives

PRC/GIT Packaging Roadmap 2002 2008 2012





Dupont Material Roadmap

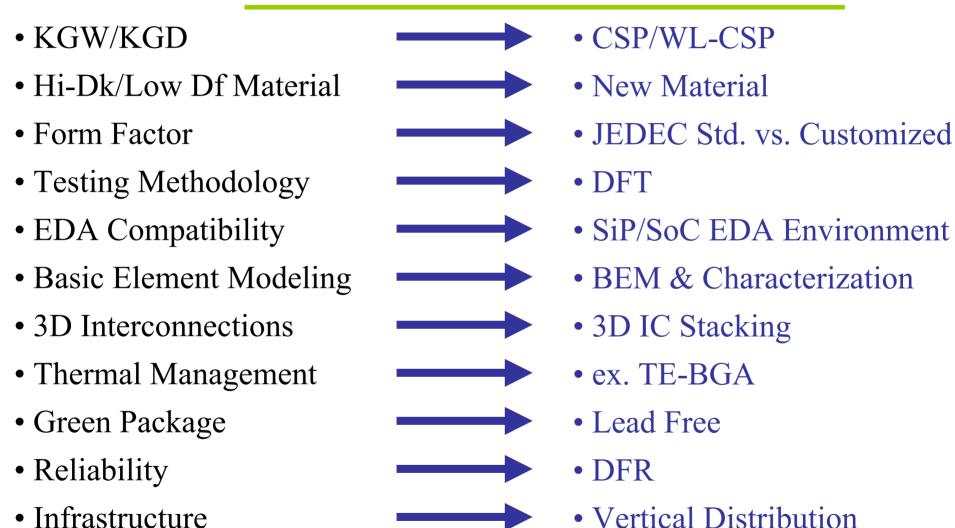
SILIM PACKAGO

COST PERFORMANCE PRODUCT SECTOR(PC)	Metric	1999	2001	2003	2009
Total Passives	Elements	1,600	2,100	3,800	5,000
Discretes	%	60%	50%	40%	25%
Arrays/Networks	%	35%	40%	45%	25%
IPDs		5%	7%	9%	10%
Integral Passives		0%	3%	6%	40%

Key Parameters for Passive Components in Hand Held Products

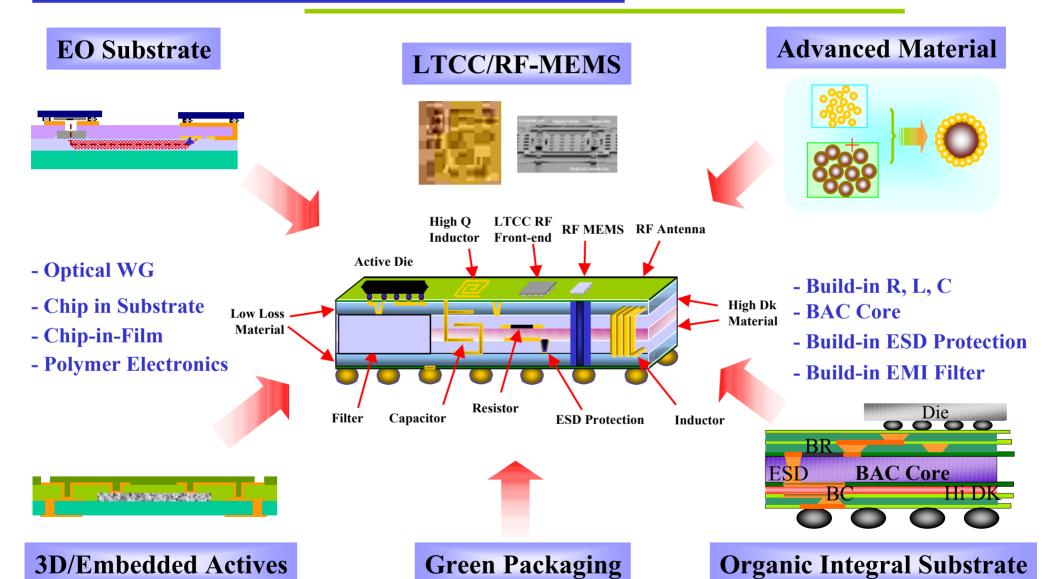


Bottlenecks & Break Through Solutions



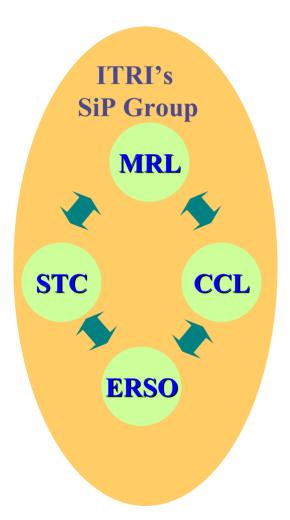


SiP in ITRI





SiP in ITRI



MRL: Organic/Polymer/Ceramic Material

STC: SoC Design/Testing

CCL: Protocol, System Partition/Integration

ERSO: SiP Design/Process/Testing, BEM,
Design Environment, Green Packaging,
Thermal/Stress Analysis/Measurement



Advanced Packaging Center/ERSO

Packaging Design

Thermal & Stress Design

- •Thermal enhanced packages
- •Advanced cooler--TE cooler, heat-pipe
- •Low stress packages--Low Dk chip

Electrical Design

- High speed digital application-- Low Noise De-Cap. / Module
- •RF application-- RF- SiP & RF-MEMS

Rapid Prototyping

- •Physical Engineering & Prototyping
- •PCB & substrate layout & Fabrication
- •SiP prototyping

Micro-Module Design

- Opto Module design & assembly
- BIO Packaging

Packaging Process Technology

Advanced Process Technology

- •Cu and Al Wafer Level Package
- •Low cost bumping, Organic Optical waveguide

Micro Structure Analysis

- •Failure Mode Analysis
- •Substrate Materials evaluation
- •Manufacturing Consultant

Assembly Process Technology

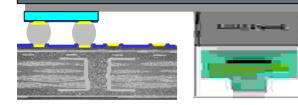
- •COF, COG
- •Flip Chip, 3D Package

→ ITRI/台南科學園區



Core Packaging Process Lab.

Assembly Process



- MAJOR EQUIPMENT
- COF bonder
- COG bonder
- OLB bonder
- Flip Chip Bonder
- Dispenser, Cleaner.
- Application
- COF, COG package
- Flip Chip, 3D Package

Advanced Process

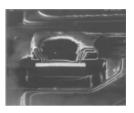




- MAJOR EQUIPMENT
- PR Coater / PI Coater / Developer
- Aligner, Sputter, Plater, Printer
- Etcher / Stripper
- Application
- Cu and Al Wafer Level Package
- Low cost bumping,
- Organic Optical waveguide

μ-Structure Analysis



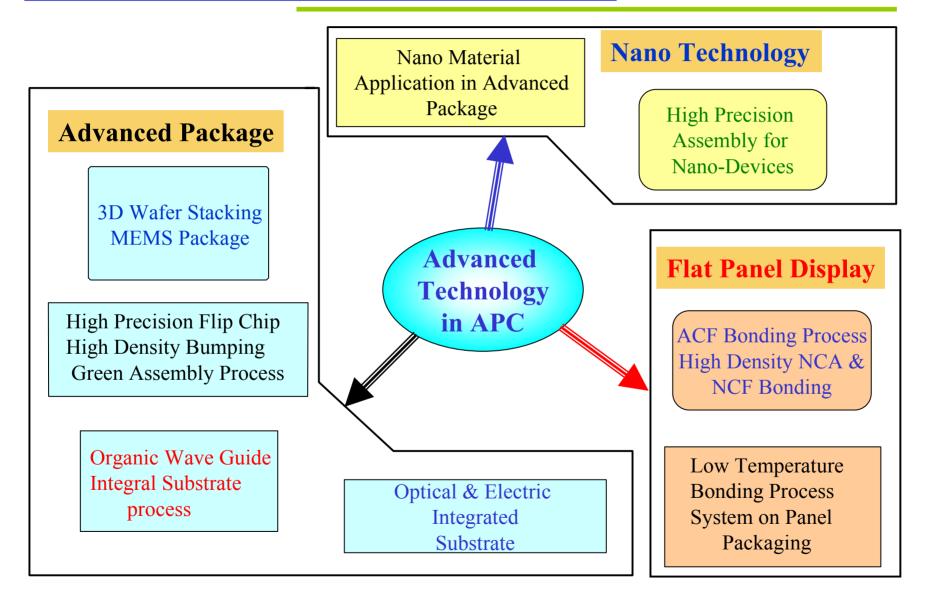


- MAJOR EQUIPMENT
- TEM / EDS
- FIB
- Auger/ESCA
- SEM / EDS
- SIMS
- Application
- •Failure Mode Analysis
- •Substrate Materials evaluation
- •Manufacturing Consultant

About 50 Engineers in Process Team

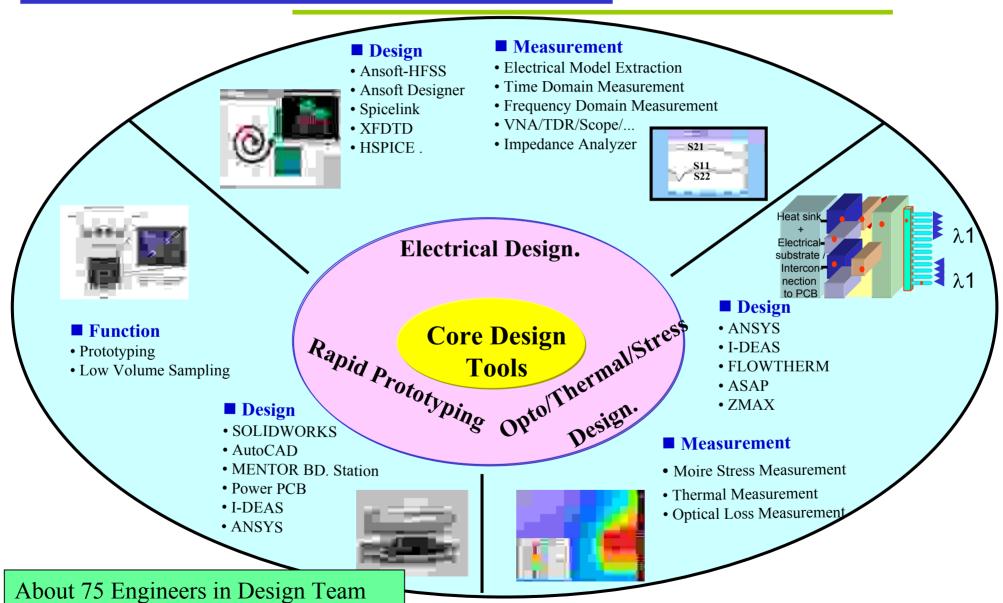


Advanced Projects in Process Team



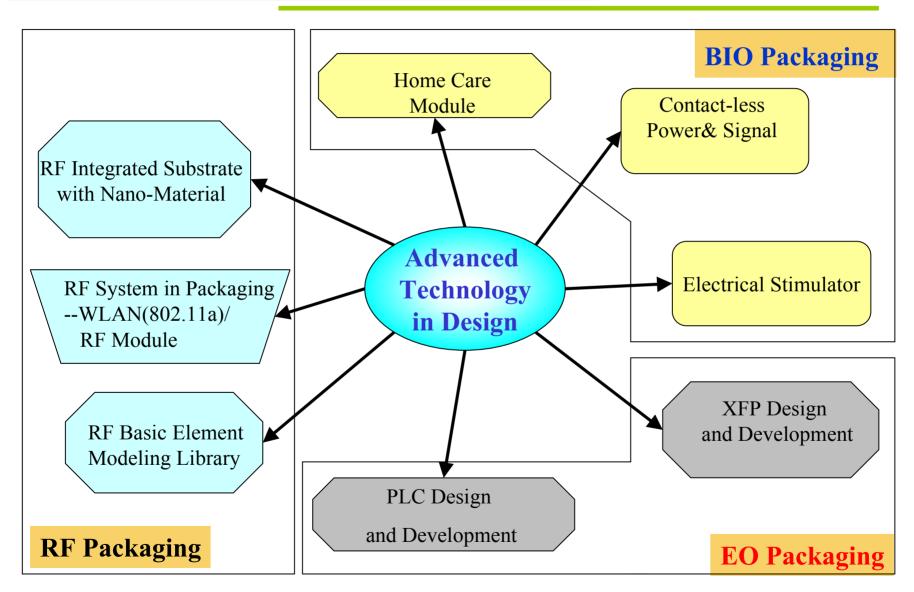


Core Packaging Design Lab.





Advanced Projects in Design Team

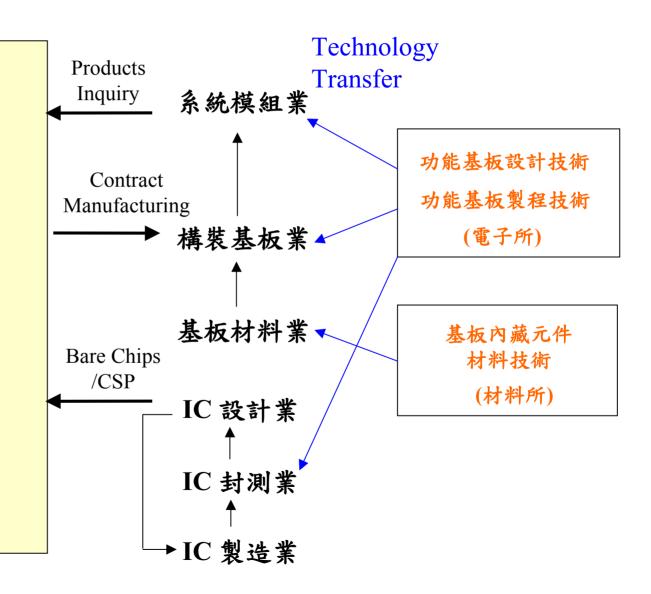




SiP 快速雛型製作服務 (SiPRPS)

SiPRPS

- Design Service
- ODM Service
- 系統分割
- •裸晶/晶片尺寸構裝來源
- 構裝結構設計
- 熱傳及應力設計
- 邏輯線路設計
- 電性設計及分析
- 基板設計及製程
- 組裝及測試
- •可靠度分析





Current Status

Material/Design/Technology/Integration all in ITRI

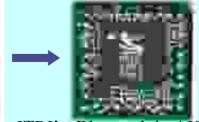
- Hi-DK (**DK=40**@6GHz) Materials Ramping up
- Fine frequency Response up to 6GHz
- Basic Element Model (BEM) <10% @6GHz
- Conventional Low Cost PCB Process
- Embedded Passives for Mixed Circuits

2.4 GHz Bluetooth Total Solution

- Worldwide 1st. Announced (ICP-2003)
- Build-in 7 Cap. & 3 Inductors
- 38% Components & 45% Area Reduced



SMD Bluetooth Module (25x15mm²)



ITRI's Bluetooth in AIS (15x15mm²)

Sanmina/ GIT /Motorola:

- Hi-DK(DK=22~36@1.9GHz) Premature Materials -- Sanmina, 3M
- Frequency Response up to 6GHz -- GIT
- BEM Modeling -- GIT (Earlier than ITRI),
- Embedded for Analog Circuits Only -- Motorola(Dk4.3@1.9GHz)

VCO Module for 1.9 GHz GSM











Motorola 1.9GHz Passives Embedded VCO



Major Index

- Highest Dk of 40 and keep on improving
- Competitive Df as low as 0.03
- Potentially highest Capacitance Density when thickness being improved in volume production

Highest manufacturing capability due to nano-composite materials

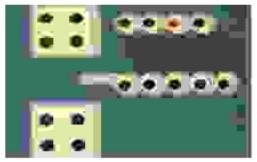
Lowest cost due to compatible to current process

Supplier	Sanmin a	Sanmin a	Vantico	DuPon t	3M	MRL/ITR I
Trademark	BC2000	EmCap	CFP	HiK	C-Ply	
Dielectric Material	FR-4	BaTiO ₃ / epoxy resin	Ceramic/ photodielectr ic	BaTiO ₃ / Polyimid e	BaTiO ₃ / epoxy resin	Nano Composite epoxy
Thickness, µm	50	100	15~20	25	25	resin 50
Dk @1GHz	4	36	23	11	22	40
Df@1GHz	0.021	0.06	0.02~0.04	0.01	0.10	<0.03
Capacitance Density, nF/in ²	0.5	2.1	10	1.5	10	8

• Current Embedded Capacitor Materials



Basic Element Modeling



Structure of Inductor



Structure of Capacitor



Accomplishment in SiP for RF Applications

2000/12

開發內藏電容元 件之2.4GHz PA (雙級串接)

EBC:9

2001/12

2003/2

開發內藏電容與電感 元件之藍芽模組開發 (包含前端射頻電路 與基頻電路)



無內藏元件

開發內藏電容與電感 元件之2.4GHz VCO(獲IMAP最佳論文獎)



EBC:3 EBL:2

EBC:7



內藏電容電感

EBC:7 EBL:3



內藏電容電感與 系統構裝整合

2003~2004

技術服務 產品應用與開發 (例:2.4GHz WLAN IEEE802.11b/g

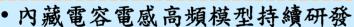


2.4GHz 內藏被動元件 系統化構裝設計 技術完備

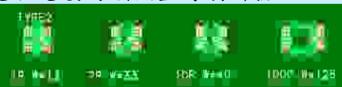


更高頻段應用研究 5GHz 射頻模組

(例:5GHz LNA,符合 **IEEE 802.11a Spec.)**



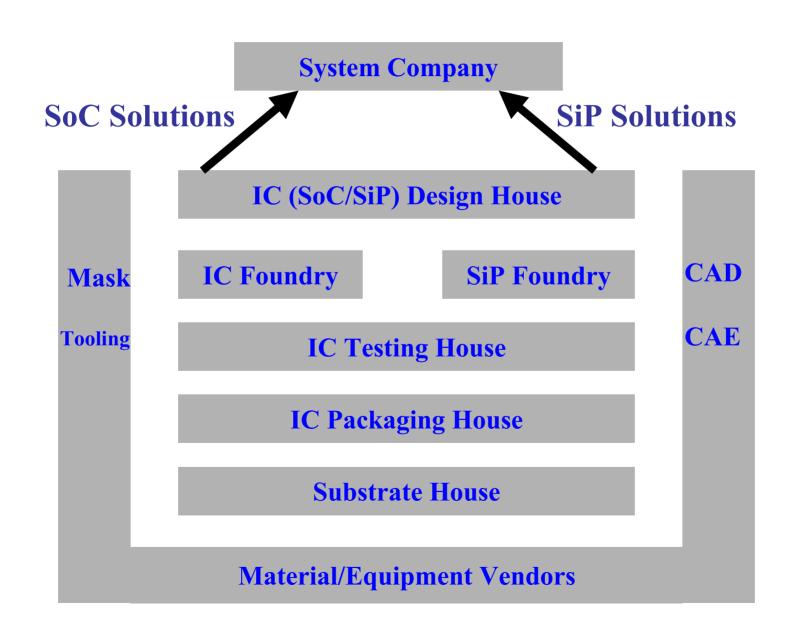






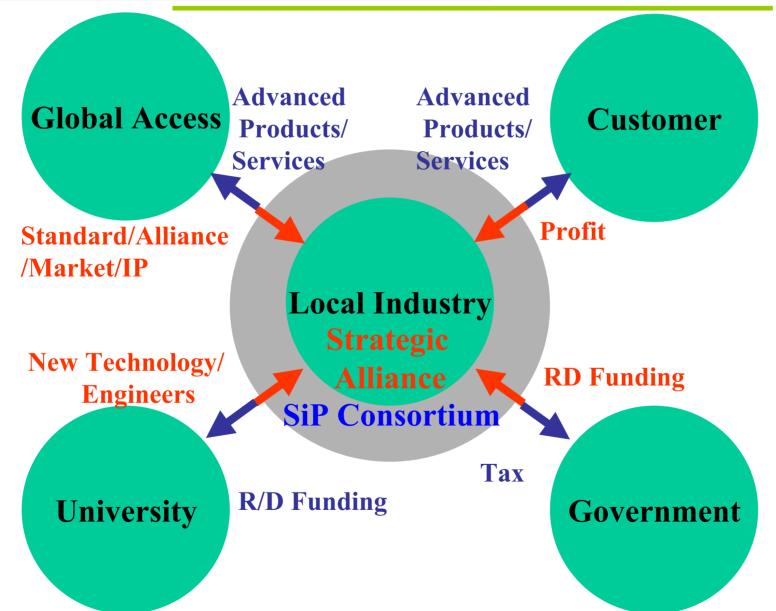


Completed Infrastructure of IC Industry





SiP Consortium Working Mechanism



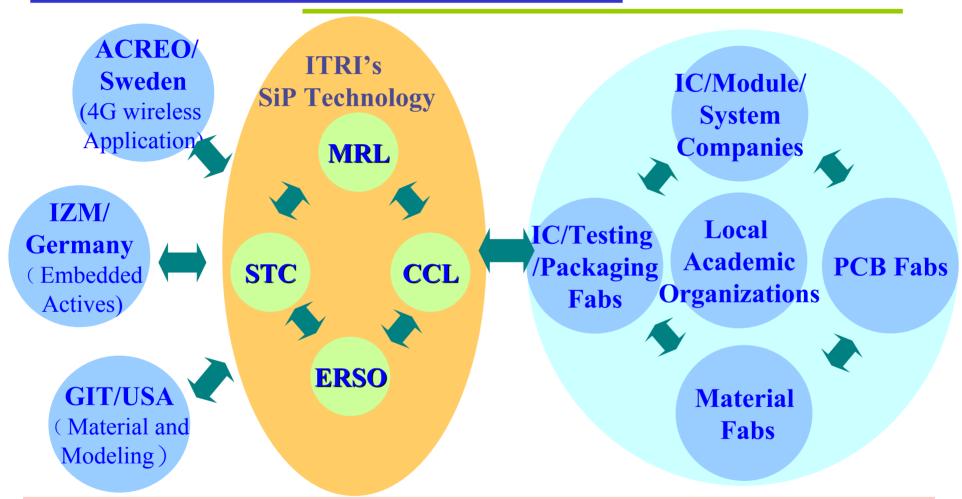


Goals of SiP Consortium

- To provide alternatives to the industry other than SoC solutions
- To back up local industry with core competency
- To mediate industry with better strategic alliance
- To help industry to develop new products & market
- To mediate local industry and MOEA for potential R/D projects
- To bridge local industry to the international opportunities



Strategy



- Aggressively involve international/local collaboration and maximize technology impact
- Upgrade local industry for the next wave competition
- Vertically integrate local industry and place Taiwan on top of the SiP Center



Action Plan

- Push for vertical integration of local industry through strategic SiP alliance.
- Establish SiP working Platform and link with current IC EDA environment.
- Establish proprietary embedded devices **BEM** and cell library by working with **EDA** companies and substrate vendors.
- Continue developing higher Dk and lower Df materials as well as key technology for substrate and process to build up entry barrier, especially in nano-technology.
- Extend applications to ESD protection for nano-devices and to de-coupling capacitance for high speed digital system.
- Establish competitive edge through IP mapping, especially on potential area.
- Push for killer applications by working with industrial system and/or module companies through either pure industrial funding or join development funding.



Thank You!